

Notice of References Cited	Application/Control No. 09/942,731	Applicant(s)/Patent Under Reexamination TAKAHASHI ET AL.	
	Examiner Steven H. Rao	Art Unit 2814	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-5,900,982	05-1999	Dolgoft et al.	359/619
	B	US-6,118,516	09-2000	Irie et al.	355/53
	C	US-5,602,679	02-1997	Dolgoft et al.	359/640
	D	US-2002/0036731	03-2002	Takahashi et al.	349/112
	E	US-2003/0076423	04-2003	Dolgoft, Eugene	348/222.1
	F	US-2003/0128917	07-2003	Turpin et al.	385/24
	G	US-2003/0197906	10-2003	Furuta et al.	359/15
	H	US-2003/0151784	08-2003	Kitamura et al.	359/3
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N	JP Utility 1997-000066	01-1997	Japan	LgZ Landis	
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
✓	U	Ronald W. Waynant and Marwood N. Ediger " Electro-Optics hand book (McGraw-Hill) , pp.2.14-2.17 (1994) (copies given to AR Olenginski at interview)
✓	V	Gregory p. Behrmann et al., " Excimer laser micromachining for rapid fabrication of diffractive optical elements " Applied optics, Vol. 36, No. 20, July 10, 1997.(copies given to AR Olenginskia t interview)
✓	W	E. Pawlowski " Thin film depostion: an alternative technique for the fabrication of bianry optics with high efficiency" (copies given to AR Olenginski at interview).
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.